

Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. (Currently Amended) A vacuum processing apparatus comprising a pressure-reduction container, exhaust means joined to said pressure-reduction container, and a processing object introducing door connected to said pressure-reduction container through a door gasket, and a ~~plurality of gaskets~~ gasket which is placed between the pressure-reduction container and said exhaust means ~~for ensuring to ensure~~ airtightness ~~[[of]]~~ between said pressure-reduction container and said exhaust means;

wherein said door gasket is made of a material with a small emission of organic matter while the ~~gaskets except the door gasket includes a gasket~~ gasket is formed by either one of a metal and a ceramic;

wherein the material with the small emission of organic matter has a relative ion intensity which does not exceed 0.1% at a molecular weight of 100 or more when it is measured by an API-MS in atmospheric-pressure Ar.

2. (Previously Presented) A vacuum processing apparatus according to claim 1, characterized in that the constituent material of said door gasket contains organic matter.

3. (Previously Presented) A vacuum processing apparatus according to claim 2, characterized in that the constituent material of said door gasket has been subjected to a process of contacting it with water at 80°C or more.

4. (Previously Presented) A vacuum processing apparatus according to claim 2, characterized in that a main component of said constituent material containing organic matter is a perfluoroelastomer.

5.-8. (Cancelled)

9. (Previously Presented) A vacuum processing apparatus according to claim 1, characterized in that said exhaust means comprises a pump and causes a small amount of an inert gas to flow upstream of said pump or at a pump purge portion.

10. (Previously Presented) A vacuum processing apparatus according to claim 1, characterized in that said exhaust means comprises a primary pump, a secondary pump connected to an exhaust side of said primary pump, and a gas introducing portion for introducing an inert gas between said primary pump and said secondary pump.

11. (Previously Presented) A vacuum processing apparatus according to claim 1, characterized in that a degree of vacuum at the time of treatment is 100 Torr or less.

12. (Previously Presented) A vacuum processing apparatus according to claim 1, characterized in that said vacuum processing apparatus is a reduced-pressure processing apparatus.

13. (Previously Presented) A vacuum processing apparatus according to claim 1, characterized in that said vacuum processing apparatus is a vapor deposition apparatus.

14. (Currently Amended) A vapor deposition apparatus according to claim 13 ~~[[1]]~~, further comprising a deposition source container.

15.-18. (Cancelled)

19. (Previously Presented) A vapor deposition apparatus according to claim 14, characterized in that an inner surface of said deposition source container contains at least one of an oxide or a nitride of an element selected from Si, Cr, Al, La, Y, Ta, Ti, and B, or C.

20. (Cancelled)

21. (Previously Presented) A vapor deposition apparatus according to claim 14, characterized in that said deposition source container contains at least one of a nitride of Al, B, or Si, C or a metal material.

22.-23. (Cancelled)

24. (Previously Presented) A vapor deposition apparatus according to claim 14, characterized in that a deposition material put into said deposition source container is an organic EL element material.

25.-27 (Cancelled)

28. (Currently Amended) An organic EL element characterized by comprising an organic layer formed by the use of the vacuum processing ~~vapor deposition~~ apparatus according to claim 1.

29. (Currently Amended) An organic EL display device characterized by comprising an organic layer formed by the use of the vacuum processing ~~vapor deposition~~ apparatus according to claim 1.

30. (Currently Amended) A vacuum processing apparatus comprising a plurality of airtight sealing members, which are different from each other in frequencies of attach/detach and which ~~are classified into~~ includes a first sealing member for sealing a door ~~[[of]]~~ used at a high frequency of the attach/detach and a second sealing member for sealing each portion except the door that is used at ~~[[of]]~~ a low frequency of the attach/detach in comparison with the door, wherein the first sealing member is formed by an organic matter subjected to an emission prevention process while the second sealing member is formed by a matter different from the organic matter;

wherein the first sealing member is subjected to the emission prevention process so that it has a relative ion intensity which does not exceed 0.1% at a molecular weight of 100 or more when it is measured by an API-MS in atmospheric-pressure Ar.

31. (Cancelled)

32. (Previously Presented) A vacuum processing apparatus according to claim 30, wherein the organic matter of the first sealing member contains a perfluoroelastomer as a main component.

33. (New) A vacuum processing apparatus according to claim 1, wherein the material with the small emission of organic matter has the relative ion intensity which does not exceed 0.01% at molecular weight of 100 or more.